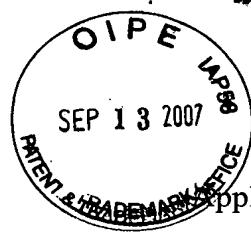


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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Matthias SLODOWSKI

Title: APPARATUS AND METHOD FOR THIN-LAYER METROLOGY

Appl. No.: 10/777,162

Filing Date: 02/13/2004

Examiner: Gordon J. Stock, Jr.

Art Unit: 2877

Confirmation No. 5100

REPLY UNDER 37 CFR 1.116

Mail Stop Box AF
Commissioner for Patents
P.O. Box 1450
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Sir:

This communication is responsive to the Final Office Action dated June 13, 2007, concerning the above-referenced patent application.

Remarks/Arguments begin on page 2 of this document.